

Overview of the Comprehensive Ion Implanter Qualification

Process

※ Pre-operational check

Check forms related to machine usage log ☐ ★

※ System introduction

System introduction (principles, panel control, three fundamental areas of the machine, main parameters and effects, etc.) ☐ ★

Introduction of main mechanisms in the three fundamental areas:

Source operation ☐ ★

Mechanisms in Terminal Module and brief introduction of its operation
(Analyzer, LMP, UMP, CMP, SMP, etc.) ☐ ★

Mechanisms in PTM Module (Decel, PFG, Profiler, Faraday Cup, E-chuck, etc.) ☐ ★

ATM / VTM mechanism and brief introduction of its operation
(Loadlock, Loadport, FOUP loading/unloading positions, etc.) ☐

※ System operation

Login ☐

System Start up (first login every day) ☐ ★

Procedures:

Load & Unload Wafers operation ☐ ★

Recipe selection and settings ☐ ★

Create Job selection and settings ☐ ★

During the implantation, if all statuses for monitoring fall in reasonable range ☐

After the implantation, product collection and turn off related mechanisms ☐ ★

Sign Off ☐

※ Others

Inter Lock handling during operation ☐